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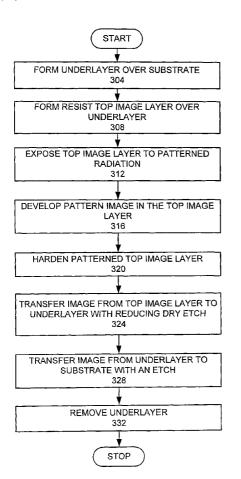
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[Continued on next page]

#### (54) Title: METHOD PROVIDING AN IMPROVED BI-LAYER PHOTORESIST PATTERN



(57) Abstract: A method for etching a feature in a layer is provided. An underlayer of a polymer material is formed over the layer. A top image layer is formed over the underlayer. The top image layer is exposed to patterned radiation. A pattern is developed in the top image layer. The pattern is transferred from the top image layer to the underlayer with a reducing dry etch. The layer is etched through the underlayer, where the top image layer is completely removed and the underlayer is used as a pattern mask during the etching the layer to transfer the pattern from the underlayer to the layer.

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According to	According to International Patent Classification (IPC) or to both national classification and IPC							
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C. DOCUM	ENTS CONSIDERED TO BE RELEVANT							
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° Special cat	tegories of cited documents:	"T" later document published after the inte	ernational filing date					
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European Patent Office, P.B. 5818 Patentlaan 2 NL - 2280 HV Rijswijk Tel. (+31-70) 340-2040, Tx. 31 651 epo nl, Fax: (+31-70) 340-3016		Thiele, N						

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